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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE	
Application of:) Atty. Docket No: LAM2P257
KO et al.) Examiner: J. Ruggles
Application No: 09/894,230) Group Art Unit: 1756
Filed: June 27, 2001) Date: December 17, 2003
For: APPARATUS AND METHOD FOR ARGON PLASMA INDUCED ULTRA VIOLET LIGHT CURING STEP FOR INCREASING SILICON-CONTAINING PHOTORESIST SELECTIVITY))))
	CERTIFICATE OF MAILING I hereby certify that this correspondence is being deposited with the United States Postal Service as First Class Mail to: Commissioner for Patents, Alexandria, VA 22313-1450, on December 17, 2003 Signed: Michael L. Gencarella
REQUEST FOR CONTINUED EXAMINATION (RCE) TRANSMITTAL	
Mail Stop: RCE Commissioner for Patents Alexandria, VA 22313-1450 Sir:	
 Submission required under 37 C.F.R. § 1.114 a. Previously submitted i. Consider the amendment(s)/reply under 37 C.F.R. § 1.116 previously 	
filed on	
iii. ☐ Other b. ⊠ Enclosed	
i. Amendment/Reply ii. Affidavit(s)/Declaration(s) iii. Information Disclosure States iv. Other	
2. Miscellaneous	dentified application is requested under 37
3. Fees a. \square Check in the amount of \$880.00 is e i. \square RCE fee required under 37 C ii. \square Extension of time fee (37 C.F) iii. \square Other	F.R. § 1.17(e); F.R. §§ 1.136 and 1.17); and
b.	
Date: December 17, 2003	ichael L. Gencarella, Esq.

Registration No. 44,703